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**Listing of Claims**

The following listing of claims will replace all prior versions, and listings, of claims in the subject application:

1. (currently amended) A liquid drop discharge head, comprising:  
a nozzle configured to discharge a liquid drop by using a piezoelectric element;  
wherein ~~lead ingredients are not included in the piezoelectric element~~ is a stacked layer type piezoelectric element formed by reciprocally stacking a piezoelectric layer and an inside electrode layer, and  
the piezoelectric layer is formed by a piezoelectric material not including lead but having bismuth sodium titanate as main ingredients, the piezoelectric material having a sintering temperature equal to or less than 1200 °C.

Claims 2-10 (canceled).

11. (currently amended) A liquid drop discharge device, comprising:  
a liquid drop discharge head configured to discharge a liquid drop;  
wherein the liquid drop discharge head includes a nozzle configured to discharge the liquid drop by using a piezoelectric element, and  
~~lead ingredients are not included in the piezoelectric element~~ is a stacked layer type piezoelectric element formed by reciprocally stacking a piezoelectric layer and an inside electrode layer, and

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the piezoelectric layer is formed by a piezoelectric material not including lead but having bismuth sodium titanate as main ingredients, the piezoelectric material having a sintering temperature equal to or less than 1200 °C.

12. (currently amended): An image forming device configured to form an image on a recording medium by discharging a liquid drop of recording liquid, comprising:

a liquid drop discharge head configured to discharge the liquid drop;  
wherein the liquid drop discharge head includes a nozzle configured to discharge the liquid drop by using a piezoelectric element, and

lead ingredients are not included in the piezoelectric element is a stacked layer type piezoelectric element formed by reciprocally stacking a piezoelectric layer and an inside electrode layer, and

the piezoelectric layer is formed by a piezoelectric material not including lead but having bismuth sodium titanate as main ingredients, the piezoelectric material having a sintering temperature equal to or less than 1200 °C.

13. (new) A liquid drop discharge head, comprising:  
a nozzle configured to discharge a liquid drop by using a piezoelectric element;  
wherein the piezoelectric element is stacked layer type piezoelectric element formed by reciprocally stacking a piezoelectric layer and an inside electrode layer,  
the piezoelectric layer is formed by a piezoelectric material not including lead but having potassium niobate as main ingredients, the piezoelectric material having a Curie temperature

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higher than a Curie temperature of PZT, and

an FPC for supplying a driving signal to the piezoelectric element is directly connected to  
an end surface electrode of the stacked layer type piezoelectric element by solder.